IN THE ABSTRACT:

Please amend the following paragraph starting at page 143, line 2 as follows:

The present invention provides a semiconductor element comprising having a semiconductor junction composed of silicon-based films, the element being characterized in that at least one of the silicon-based films containing a microcrystal, and microcrystal. The microcrystal is located in at least one interface region of the silicon-based films film containing the microcrystal and has no orientation property. Further, the present invention provides a semiconductor element comprising having a semiconductor junction composed of silicon-based films, wherein at least one of the silicon-based films contains containing a microcrystal, and the orientation property of the microcrystal in the silicon-based film containing the microcrystal changes changing in a film thickness direction of the silicon-based film containing the microcrystal. In order to provide an inexpensive silicon-based film showing excellent performance, the present invention provides a Thereby, a silicon-based film having a shortened tact time, an increased film forming rate, and excellent characteristics, and a semiconductor element including this silicon-based film, and a semiconductor element using this silicon-based film and having excellent adhesion and environmental resistance can be obtained.

